

<b>Notice of References Cited</b>	Application/Control No. 10/632,176	Applicant(s)/Patent Under Reexamination FARROKH ET AL	
	Examiner Donghee Kang	Art Unit 2811	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	No et al., "The HARPSS Process for Fabrication of Nano-Precision Silicon Electromechanical Resonators", IEEE Conf. of Nanotechnology, pp 489-494, October 30, 2001.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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